

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
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[illegible]

LMF	CA	A. Friedberger et al.; A Versatile And Modularizable Micromachining Process For The Fabrication Of Thermal Microsensors And Microactuators; Journal of Micromechanics and Microengineering; 9/7/2001; pp. 623-629.
	CB	Ivonne Schneegaß, et al.; Miniaturized Flow-Through PCR With Different Template Types In A Silicon Chip Thermocycler; Institute of Physical High Technology; 8/9/2001; pp. 1-16.
	CC	John S. Suehle, et al.; Tin Oxide Gas Sensor Fabricated Using CMOS Micro-Hotplates and <i>In-Situ</i> Processing; IEEE Electron Device Letters; Vol. 14, No. 3, March, 1993; pp. 118-120.
	CD	*Yukikio Hosoda et al.; Fabrication And Applications Of Polymer-Based Microchannel-Heater Chip As Microreactor; Micro Total Analysis Systems, 2002.
	CE	*J. Laconte et al.; SOI CMOS Compatible Low-Power Microheater Optimization And Fabrication For Smart Gas Sensor Implementations; IEEE International Conference on Sensors; 2002.
	CF	*Gwi-Yang Chung et al.; The Fabrication Of Micro-Heaters With Low-Power Consumption Using SOI And Trench Structures; Metals and Materials International; 2002.
	CG	*V. Guarnieri et al.; Low-Power Silicon Microheaters On A Thin Dielectric Membrane With Thick-Film Sensing Layer For Gas Sensor Applications; Microelectronics, Microsystems and Nanotechnology; 2000.
LMF	CH	*Yaowu Mo et al.; Low-Voltage And Low-Power Optimization Of Micro-Heater And Its On-Chip Drive Circuitry For Gas Sensor Array; Sensors and Actuators, A: Physical, 2002.

EXAMINER <i>L. A. Torsing</i>	DATE CONSIDERED <i>3/11/05</i>
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**OTHER DOCUMENTS** (including Author, Title, Date, Pertinent Pages, Etc.)

LMF	CI	*W. C. Tian et al.; Freestanding Microheaters In Si With High Aspect Ratio Microstructures; Journal of Vacuum Science & Technology, B: Microelectronics and Nanometer Structures; 2002.
	CJ	*Tailian Chen et al.; Coalescence Of Bubbles In Nucleate Boiling On Microheaters; International Journal of Heat and Mass Transfer; 2002.
	CK	*A. V. Korlyakov et al.; Infrared Microradiator Based On SiC-on Insulator Thin-Film Structures; Journal of Optical Technology; 2001.
	CL	*Y. Mo. et al.; Micro-Machined Gas Sensor Array Based On Metal Film Micro-Heater; Sensors and Actuators, B: Chemical; 2001.
	CM	*Gwi-Sang Chung et al.; Fabrication Of Pt Microheater Using Aluminum Oxide As A Medium Layer And Its Characteristics; Sensors and Materials; 1998.
IAF	CN	*Carole Rossi et al.; Realization And Performance Of Thin SiO <sub>2</sub> /SiN <sub>x</sub> Membrane For Microheater Applications; Sensors and Actuators, A: Physical; 1998.

\*ABSTRACT ONLY

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